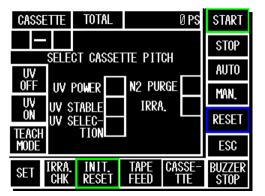
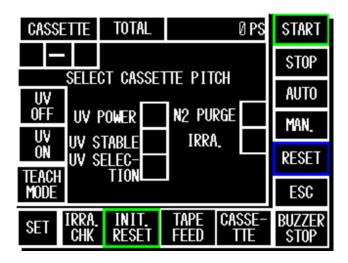
## 5.2 Manual operation for aligner





(1) Press [Q. STOP] key.

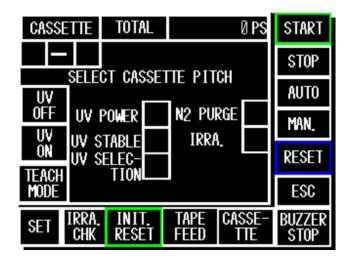


(2) Press [BUZZER STOP] key on MAIN SCREEN.

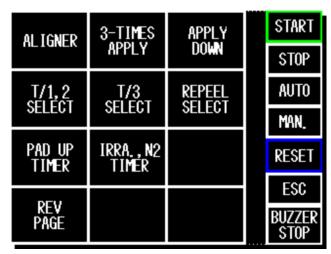


- (3) Connect the teach pendant with the machine, and press [TEACH MODE] key on the MAINSCREEN.
- (4) Press [MAINTENANCE] key on the teach pendant. "RANDOM" is displayed on the teach pendant screen. Press [BUZZER STOP] key on MAIN SCREEN.

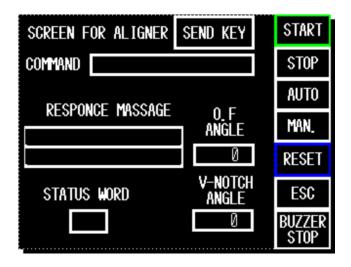
# 5.2 Manual operation for aligner (Continued)



(5) Press [MAN.] key on MAIN SCREEN.
"1<sup>st</sup> page of the setting screen" is displayed.
Press [REV PAGE].



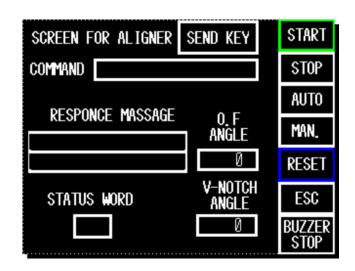
(6) Press "ALIGNER". "SCREEN FOR ALIGNER" is displayed.



(7) Press display of "COMMAND". The keyboard is indicated.

## 5.2 Manual operation for aligner (Continued)

- (8) Enter the command\* with the keyboard according to the following procedure.
  - (a) Enter "P0" (P Zero).
  - (b) Enter appropriate command\*. Enter a numerical value after the command when necessary.
  - (c) Press [SPACE] key on the keyboard.
  - (d) Press [ENT] key to input the value.
- \* Refer to next page about the command.



- (9) Press [SEND KEY]. The command is sent to the aligner.
- (10) To finish the manual operation, press [ESC] key, and then press [AUTO] key.

#### <Exit from the manual operation>

- (1) Press [ESC] key on "SCREEN FOR ALIGNER", then press [AUTO] key to back to MAIN SCREEN.
- (2) Confirm whether "RANDOM" is displayed on the screen of the teach pendant. If "RANDOM" is not displayed, press [AUTO/TEACH] key to indicate "RANDOM". Press [MAINTENANCE] key on the teach pendant. The display on the teach pendant is disappeared.
- (3) Press [TEACH MODE] key on MAIN SCREEN, and disconnect the teach pendant from the machine.

### 5.2 Manual operation for aligner (Continued)

### Command type:

BW: Switches to the alignment operation for T3. Only the wafer centering is

performed without V-notch detection.

FW <offset>: Aligns the wafer at an offset angle you input.

(The offset angle is 0-degree if the value is not input)

GW: The offset angle ("SR" command) is read from the battery backup RAM, and

aligns the wafer.

RC: The vacuum pad is moved to the reference position.

RS: Reset the aligner.

RX <step>: Moves X-axis direction by an increment of the step. RY <step>: Moves Y-axis direction by an increment of the step.

RW <step>: Turns the pad by an increment of the step.

SF: Sets the OF detect mode.
SN: Sets the Notch detect mode.

SR<Offset>: It is used with GW command. Inputs the previous offset angle to the battery

backup RAM.

SX: Change the CCD unit size. (Enter the wafer size to "X")

VN: Turns on vacuum. VF: Turns off vacuum.

CCD correction

CB: Corrects the CCD

<sup>\*</sup> Described "Command <step / setting value>" is requires to input the value in <> when you input the value.